

DETAILED ACTION

This action is to replace the action mailed 19 February 2010.

Allowable Subject Matter

1. Claims 1, 3-4, 9-12, 19-22, 29-31, 33-34, 37-38 and 40-60 are allowed.
2. The following is an examiner's statement of reasons for allowance: The prior art of record fails to teach or fairly suggest a semiconductor manufacturing apparatus comprising: a plasma generating device capable of generating a plasma; a first chamber for performing a plasma treatment on a first part of an object by the plasma therein under atmospheric pressure or approximate atmospheric pressure; a rail for sliding the plasma generating device, the rail provided in the first chamber; and an ink-jet device capable of applying a droplet to a second part of the object simultaneously with performing the plasma treatment, wherein the plasma generating device is provided in the first chamber, wherein the ink-jet device is provided in a second chamber; and wherein the object is level transferred (i.e. capable of being transferred horizontally) in the first chamber along a first direction and the plasma generating device is moved in the first chamber along the rail and along a second direction intersecting with the first direction and in a direction parallel to a side of the object.
3. Further, no other prior art was located that fairly suggested the claimed invention in whole or in part, along with the requisite motivation for combination, to anticipate or render the claimed invention obvious.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Response to Arguments

4. Applicant's arguments, filed 6 January 2010, with respect to amended claims 1, 3-4, 9-13, 19-22, 29-31, 33-34, 37-38 and 40-60 have been fully considered and at least some are persuasive. More specifically, the prior art of record fails to disclose a semiconductor manufacturing apparatus comprising first and second chambers in which the claimed plasma generating device and ink-jet device are respectively located, wherein the apparatus is capable of simultaneously treating both first and second parts of a single object using the plasma generating device and the in-jet device. Thus, the previously issued rejections have been withdrawn.
5. In order to pass this application to issue, all pending withdrawn claims, except claim 13, which has been rejoined, will need to be cancelled.

Conclusion

Any inquiry concerning this communication or earlier communications from the examiner should be directed to KARLA MOORE whose telephone number is (571)272-1440. The examiner can normally be reached on Monday-Friday, 9:00 am-6:00 pm.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Parviz Hassanzadeh can be reached on 571.272.1435. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see <http://pair-direct.uspto.gov>. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free). If you would like assistance from a USPTO Customer Service Representative or access to the automated information system, call 800-786-9199 (IN USA OR CANADA) or 571-272-1000.

/Karla Moore/
Primary Examiner, Art Unit 1792